



03-12-04  
Express Mail No. ER534275246US  
Attorney Docket No.: MS-001

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF: Boris Kobrin et al.

§ GROUP ART UNIT: Unknown

SERIAL NO.: 10/759,857

§

§

§ EXAMINER: Unknown

FILED: January 16, 2004

§

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FOR: APPARATUS AND METHOD FOR CONTROLLED  
APPLICATION OF COATINGS FROM A  
CHEMICALLY REACTIVE VAPOR SOURCE

§

§ Attorney Docket No.:

§ MS-001

Date: March 10, 2004

**INFORMATION DISCLOSURE STATEMENT**  
**TRANSMITTAL LETTER**

**Hon. Commissioner for Patents**  
**P.O. Box 1450**  
**Alexandria, Virginia 22313-1450**

Sir:

Applicants are submitting the subject Information Disclosure Statement under 37 CFR § 1.97(b)(1). This Information Disclosure Statement is being submitted within three (3) months of the filing date of the subject application.

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**CERTIFICATE OF MAILING UNDER 37 CFR § 1.10**

I hereby certify that this paper is being deposited with the U.S. Postal Service on the date shown below with sufficient postage as U.S. EXPRESS MAIL NO. ER534275246US in an envelope addressed to: Mail Stop DD, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Date: March 10, 2004

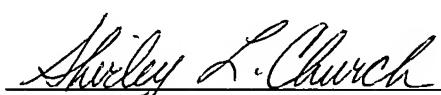
  
\_\_\_\_\_  
Shirley L. Church, Reg. No. 31,858

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Applicants do not believe that any fee is due in connection with the filing of this Information Disclosure Statement under 37 CFR § 1.97(b)(1). However, in the event that any additional fee is due, the Commissioner is hereby authorized to charge Deposit Account No. 50-1512 of Shirley L. Church, Sunnyvale, California, in the amount of such fee.

This transmittal letter is submitted in duplicate for accounting purposes.

Respectfully submitted,

  
\_\_\_\_\_  
Shirley L. Church  
Registration No. 31,858  
Attorney for Applicants

Correspondence Address:  
Shirley L. Church, Esq.  
P.O. Box 61929  
Sunnyvale, CA 94088



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Date: March 10, 2004

**INFORMATION DISCLOSURE STATEMENT  
UNDER 37 CFR § 1.97(b)(1)**

**Hon. Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450**

Sir:

In accordance with 37 CFR § 1.97(b)(1), applicants hereby request consideration of this Information Disclosure Statement. This Information Disclosure Statement is being submitted within three (3) months of the filing date of the subject application. Applicants are providing herewith a copy of each document cited on the attached Form PTO-1449.

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**CERTIFICATE OF MAILING UNDER 37 CFR § 1.10**

I hereby certify that this paper is being deposited with the U.S. Postal Service on the date shown below with sufficient postage as U.S. EXPRESS MAIL NO. ER534275246US in an envelope addressed to: Mail Stop DD, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

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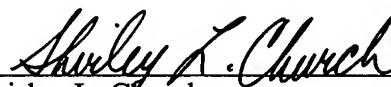
  
\_\_\_\_\_  
Shirley L. Church, Reg. No. 31,858

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The submission of this Information Disclosure Statement and Form PTO-1449 is not an admission that the art cited is "prior art" with respect to the present invention, nor is it a representation that no better art exists. Applicants hereby reserve the right to swear behind or otherwise disprove any alleged "prior" nature of any art cited should the facts support and the situation warrant such an action.

If the Examiner has any questions, s/he is respectfully requested to contact the undersigned attorney at the telephone number set forth below.

Respectfully submitted,

  
\_\_\_\_\_  
Shirley L. Church  
Registration No. 31,858  
Attorney for Applicants  
(650) 473-9700

Correspondence Address:  
Shirley L. Church, Esq.  
P.O. Box 61929  
Sunnyvale, CA 94088



FORM PTO-1449  
(Equivalent)

U.S. Department of Commerce  
Patent and Trademark Office

U.S. Application Serial No.  
10/759,857

Atty. Docket No.  
MS-001

INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT

(Use several sheets if necessary)

Boris Kobrin et al.  
Applicants

January 16, 2004  
Filing Date

Unknown  
Group

U. S. PATENT DOCUMENTS

Examiner Initial	Document Number	Issue Date	Name	Class	Subclass	Filing Date If Appropriate
	5,576,247	11/19/96	Yano et al.	437	225	
	5,602,671	02/11/97	Hornbeck	359	224	
	5,626,924	05/06/97	Ishikawa	427	759	
	6,203,505	03/20/01	Jalisi et al.	600	585	
	6,383,642	05/07/02	Le Bellac et al.	428	412	
	6,576,489	06/10/03	Leung et al.	438	52	

U. S. PATENT APPLICATION DOCUMENTS

Examiner Initial	Document Number	Publication Date	Name	Class	Subclass	Filing Date
	2001/0028924A1	10/11/01	Sherman	427	255.28	05/24/01
	2002/0031618A1	03/14/02	Sherman	427	569	10/09/01
	2002/0033229A1	03/21/02	Lebouitz et al.	156	345	04/20/01

Examiner                      Date Considered

Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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### U. S. PATENT APPLICATION DOCUMENTS

<u>Examiner Initial</u>	<u>Document Number</u>	<u>Publication Date</u>	<u>Name</u>	<u>Class</u>	<u>Subclass</u>	<u>Filing Date</u>
	2002/0076507A1	06/20/02	Chiang et al.	427	569	06/20/02
	2002/0146725A1	10/10/02	Mullen et al.	435	6	11/09/01
	2002/0195950A1	12/26/02	Mikhael et al.	315	111.21	08/26/02
	2003/0035904A1	02/20/03	Hsieh et al.	427	569	08/16/01
	2003/0040173A1	02/27/03	Fonash et al.	438	622	08/14/02
	2003/0138645A1	07/24/03	Gleason et al.	428	447	10/29/02

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### FOREIGN PATENT DOCUMENTS

<u>Examiner Initial</u>	<u>Document Number</u>	<u>Publication Date</u>	<u>Name</u>	<u>Class</u>	<u>Subclass</u>	<u>Filing Date If Appropriate</u>
	JP 11116278	04/27/99	Hiromi et al.	C03C	17/28	
	WO 02/28956	04/11/02	Murphy et al.	C08L	1/28	

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### OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

- W. R. Ashurst et al., "Wafer Level Anti-Stiction Coatings With Superior Thermal Stability", Presentation at Hilton Head, South Caroline meeting, pp 1 - 4 (June 2002). Contact ashurbr@uclink4.berkeley.edu.
- W. R. Ashurst et al., "Vapor Phase Anti-Stiction Monolayer Coatings for MEMS", TDMR-Draft, pp. 1 - 6 (Sept 2003).
- W. R. Ashurst et al., "Wafer level anti-stiction coatings for MEMS", Sensors and Actuators A, Elsevier Science B.V., Vol. 104, pp. 213 - 221 (2003).

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<u>Examiner</u>	<u>Date Considered</u>
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**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)**

- M. V. Collins et al., "Optimization of Anodic Bonding to MEMS with Self-Assembled Monolayer (SAM) Coatings", Reliability, Testing, and Characterization of MEMS/MOEMS, Proceedings of SPIE, Vol. 4558, pp. 234 - 241 (2001).

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X. Wang et al., "Gas-Phase Silicon Etching with Bromine Trifluoride", Transducers, International Conference on Solid State Sensors and Actuators, Chicago, pp. 1505 - 1508 (June 1997).

Y. Wang et al., "Vapor phase deposition of uniform and ultrathin silanes", SPIE, Vol. 3258, pp. 20 - 28 (1998).

**Examiner** \_\_\_\_\_ **Date Considered** \_\_\_\_\_

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